Sputter tool – Denton Explorer 14

- Depositing **Cr, Al, Ag, NiO, ZnO, AZO layers**
- Sample Sizes: Pieces – 6″ wafer
- Target Size: 3 inch
- Base Pressure ~ $2.2\text{x}10^{-6}$ Torr
- Pump Time ~ 3 Hours
- Operation Gas Flow ~ Ar, 30sccm
- RF or DC